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Akiyama

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[54] DOUBLE-BEAM SPECTROPHOTOMETER
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[56] References Cited
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[57] ABSTRACT

A double-beam spectrophotometer which uses an integrating sphere for measurement of the total reflected light from a sample or only the diffuse reflection component thereof. The sphere is provided with a first pair of windows in which a sample and a reference are detachably and exchangeably set and a second pair of windows through one of which one of a sample and a reference light beam enters the integrating sphere so as to impinge perpendicularly on said sample or reference set in one of said first pair of windows, while through the other of said second pair of windows the other of said sample and reference light beams enters said integrating sphere to impinge aslant on said reference or sample set in the other of said first pair of windows. The positions of said sample and reference are exchanged in accordance with the type of measurement to be made.

6 Claims, 8 Drawing Figures

